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High energy protons channeling and volume reflection effects through a bent germanium crystal

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for the COHERENT experiment

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Ge for beam deflection: theoretical considerations

✓ **Crystal perfection is mandatory:** dislocations free (or at least Etch Pits Density $< 10^2/\text{cm}^2$) materials must be acquired.

⇒ Si fulfils the requirement. Until a decade ago, Si was by far the best choice...

⇒ Thanks to the renewed interest towards Ge (multijunction solar cells, MOSFET, graded Si-Ge alloys) now Ge crystals with EPD $\approx 0/\text{cm}^2$ are available.

✓ **Ge potential benefits...**(in theory)

Higher Z as compared with Si (32 vs 14) implies

⇒ stronger equivalent magnetic field (scales with Z)

⇒ higher critical angle for both axial and planar channeling (scales with \sqrt{Z})

✓ **Ge drawbacks....**(in practice)

⇒ extremely brittle! (crystal damage inflicted by cutting can propagate deeply)

⇒ lower reactivity as compared to silicon (ΔH_{GeO_2} -132 vs ΔH_{SiO_2} -217 Kcal/mol)... Etching must contain always an oxidant and a complexing agent....

From Ge wafers to the final strip...

WEDM cut, B etch, 12 min

Acc.V Spot Magn Det WD Exp | 20 µm
10.0 kV 3.5 3200x SE 8.0 1 Ge umi WEDM 110 18:3:5 12'

Dicer cut, B etch, 12 min

Acc.V Spot Magn Det WD Exp | 20 µm
10.0 kV 3.0 3200x SE 8.5 40 Ferr B 12'

WEDM cut, A etch, 12 min

Acc.V Spot Magn Det WD Exp | 20 µm
10.0 kV 3.5 3200x SE 10.2 1 Ge umi WEDM, 3:1, 12'

Dicer cut, A etch 12 min

Acc.V Spot Magn Det WD Exp | 20 µm
10.0 kV 3.0 3200x SE 8.3 40 Ferr A 12'

lower
result

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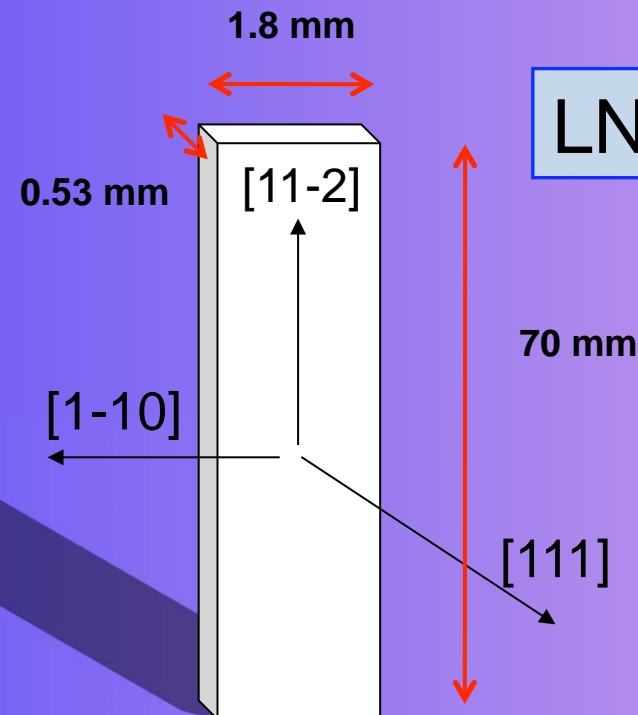
A few points concerning the processing route...

✓ You had only a quick glance... About 120 strips were cut, etched and analyzed...

✓ The EPD claimed by the factory ($0 / \text{cm}^2$) was also tested by applying anisotropic chemical etching (Superoxol, $\text{H}_2\text{O}_2 : \text{HF} : \text{H}_2\text{O}$, 1 : 1 : 4), followed by inspection with optical microscopy and Etch Pits count....

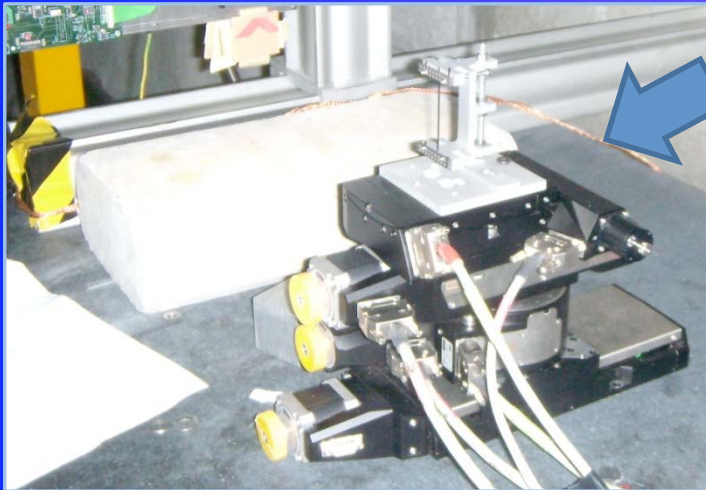
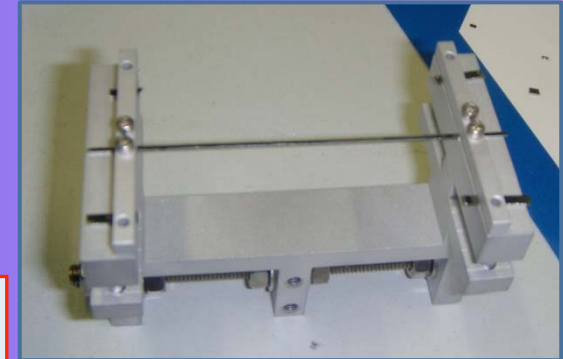
✓ It was confirmed that EPD in the bulk is really $0 / \text{cm}^2$!

✓ The **chosen strip** was dicer cut,
etched with B composition for 12 min.
It was selected since displayed the best
results as for surface morphology and
crystal quality



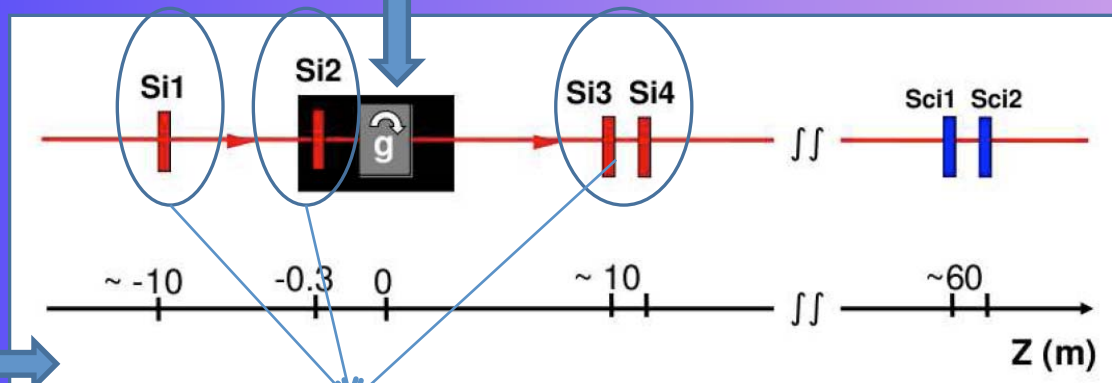
Tests with High Energy Protons CERN SPS H8 400 GeV: June 2010

Ge strip mounted on the strip holder
(Ferrara University) for bending



High precision
goniometer (INFN-LNL)
2 translation stages
2 rotation stages (1 μ rad
accuracy)

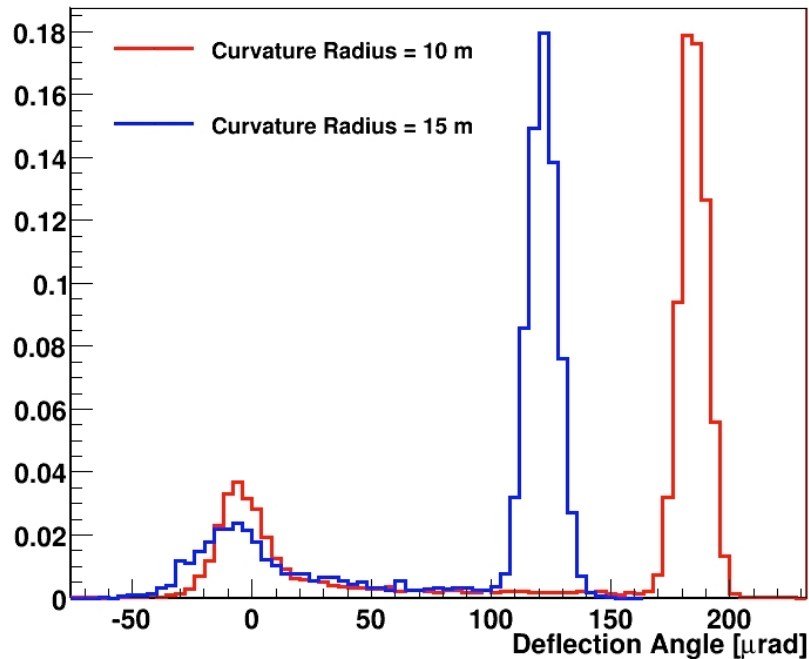
Sketch of the experimental
set-up (Coherent
experiment)



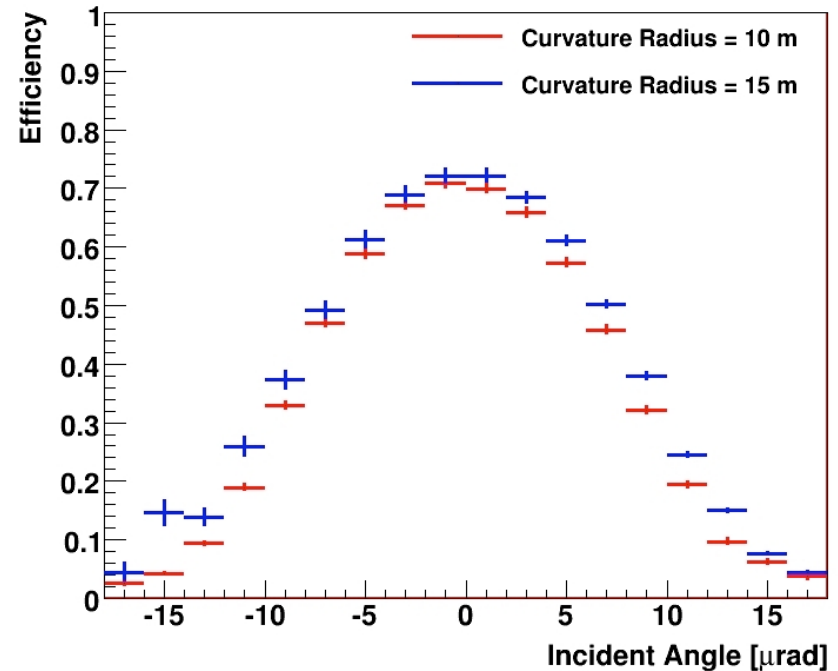
Particle trajectory
reconstruction

Planar channeling with 2 curvatures

Germanium {111} Planar Channeling

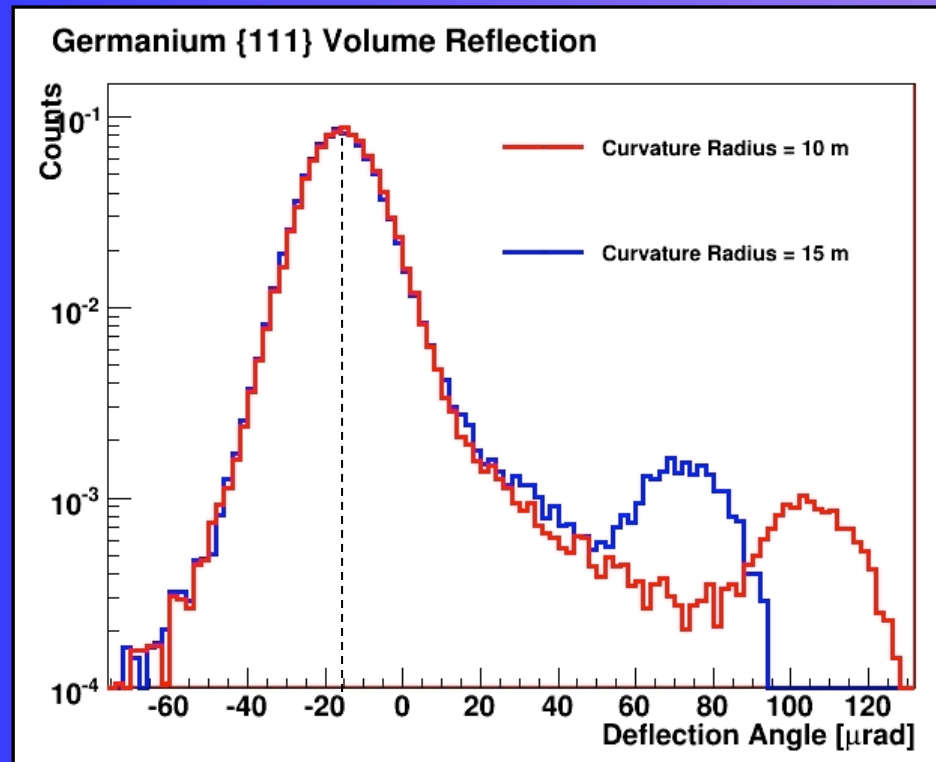


Germanium {111} Planar Channeling Efficiency



Curvature radius R (m)	10	15
Deflection (μrad)	185 ± 2	122 ± 2
Maximum Efficiency (%)	70.5 ± 1.0	72.5 ± 1.0
FWHM/2 (μrad)	8.6 ± 0.1	9.2 ± 0.1

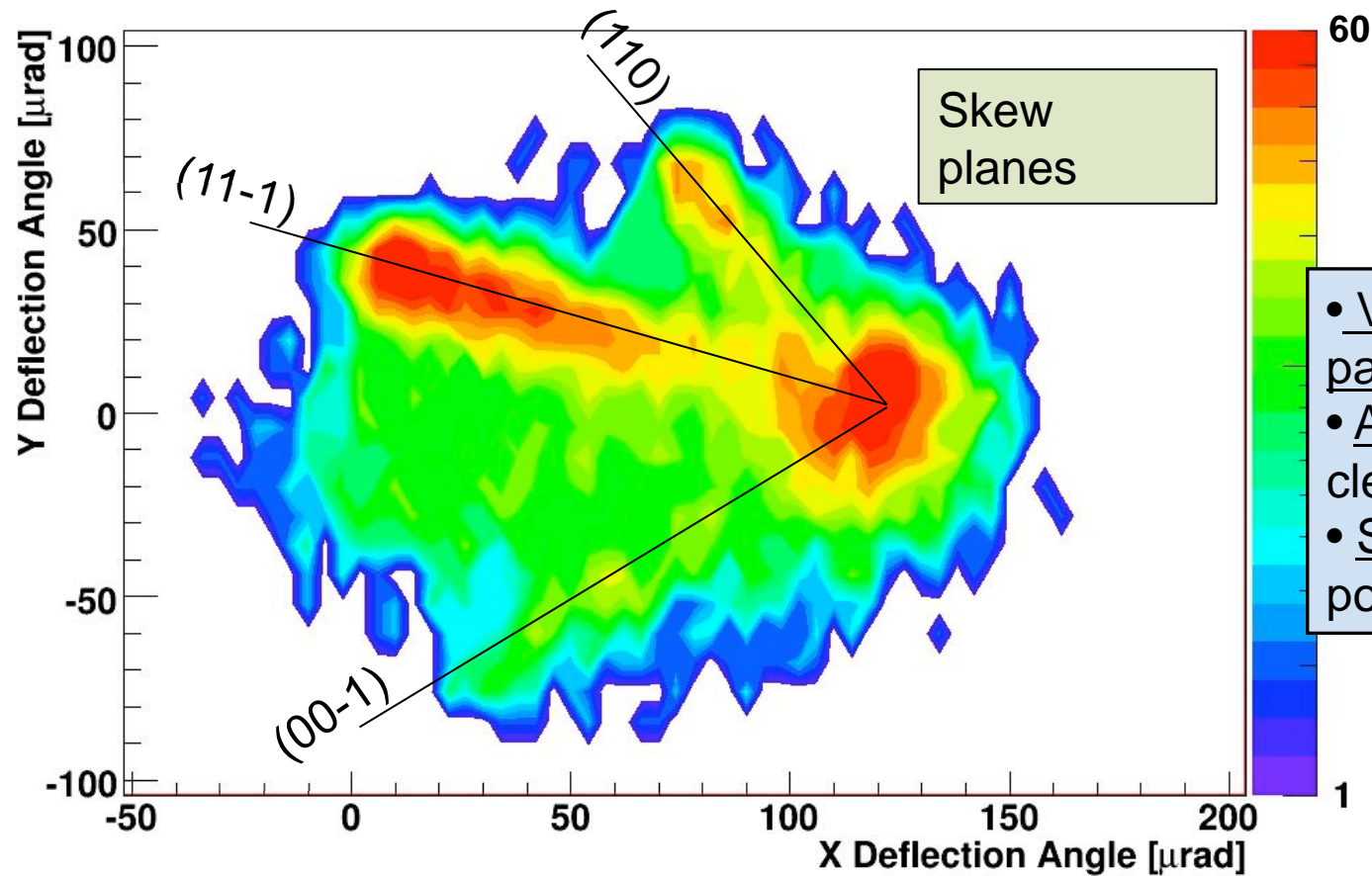
Volume reflection with 2 curvatures



Curvature radius R (m)	10	15
Deflection (μrad)	15.3 ± 0.2	15.9 ± 0.2
Efficiency $[-\infty, +3\sigma]$ (%)	95.9 ± 0.4	95.3 ± 0.4

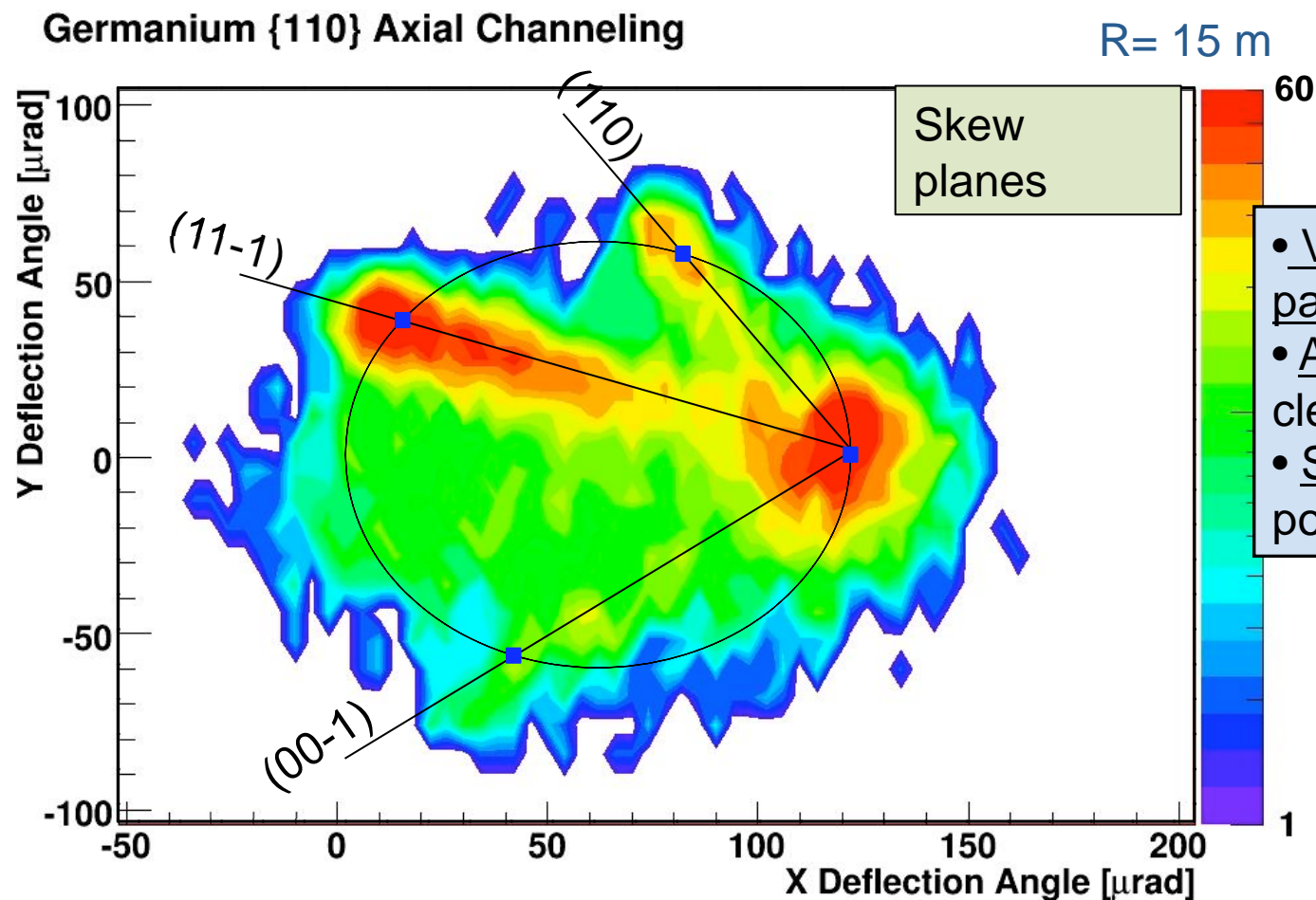
[110] axial channeling: preliminary analysis

Germanium {110} Axial Channeling $R = 15 \text{ m}$



- Very few undeflected particles
- Axial deflection is clearly visible
- Skew planes are also populated

[110] axial channeling: preliminary analysis



- Very few undeflected particles
- Axial deflection is clearly visible
- Skew planes are also populated

A (not straightforward) comparison...

We cannot compare directly with previous results, neither Si or Ge...

- **different orientation or**
- **different curvature radius or**
- **different beam path**

1994, S.P. Moller et al., Si (111), $R=35.7$ m strip $50 \times 10 \times 0.9$ mm, protons 450 GeV, Beam Div. $3 \mu\text{rad}$

50

1998, C. Biino et al., Ge (110), $R=60$ m strip $50 \times 10 \times 1$ mm, protons 450 GeV, BD $3 \mu\text{rad}$

60

2008, W. Scandale et al., Si (111), $R = 8.6$ m, strip $1.85 \times 70 \times 0.5$ mm, protons 400 GeV, max eff

44

2009, W. Scandale et al., Si (110), $R = 38$ m, strip $1.94 \times 70 \times 0.5$ mm, protons 400 GeV, max eff

83.4

This work, Ge (111), $R = 15$ m, strip $1.8 \times 70 \times 0.5$ mm, protons 400 GeV, max eff

72.5

Planar channeling efficiency (%)

Concluding remarks and future planning

- ❖ Two different cut techniques were tested (WEDM and dicer).
Dicer was more reproducible (though a deeper study of WEDM cut is in progress).
- ❖ Wet etching was used for the damaged layer removal
Ge strip displaying the best crystal quality (HRXRD) was selected
(B etch, 12 min)
- ❖ The chosen strip proved to deflect a 400 GeV proton beam with high efficiency by both **planar channeling** and **volume reflection**
- ❖ To the best of our knowledge, for the first time **axial channeling** in this energy regime was observed for germanium
- ❖ In order to improve crystal quality of the beam entry surface, mechanical polishing prior to etching will be our next issue.
- ❖ **Ge crystals <110>** oriented will be searched for....
(higher interplanar distance)

Thank you